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## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application: Furukawa, et al

Group Art Unit: 2823

Serial No.: 09/599,783

Examiner: Julio J. Maldonado

Filed: 06/22/2000

Title: Method For Etching A Semiconductor  
Substrate Using Germanium Hard MaskENTERED  
OSmails-logu  
2/13/03Assistant Commissioner of Patents  
Washington, D.C. 20231FAX COPY RECEIVED  
OCT 25 2002RESPONSE TO FINAL REJECTION

TECHNOLOGY CENTER 2800

Sir:

In response to the Office Action of Oct 1, 2002, kindly enter of the following:

## CERTIFICATE OF TRANSMISSION UNDER 37 CFR 1.8

I certify that this correspondence of 19 pages is being transmitted by facsimile to the United States Patent and Trademark Office to: Examiner Julio J. Maldonado, Art Unit 2823 at facsimile number 703 872-9319 on October 2, 2002 by Arnette Dodge.

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